Tuning the CEOS STEM Corrector

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Tuning Prerequisites.

- Use a standard specimen Au nanoparticles on carbon.
- Microscope must be absolutely stable: ie no thermal drift, lens hysteresis, stage drift, HT instability etc. Typically, this means changing the microscope voltage on a Friday and tuning on the following Monday.
- Specimen must free from contamination. Ideally, the specimen should be left in the microscope overnight. It must be beam showered.
- Instabilities will make tuning difficult and invalidate the long-term stability of the tune.



Aberrations

Symbol	Order	Name	Target Value	How to Adjust
A1	1 st	2-fold Astigmatism	0-5nm	Manual: Coarse stigmators
C1	1 st	Focus	5-10nm	Manual: Focus
A2	2 nd	3-fold Astigmatism	<50nm	Corrector
B2	2 nd	Coma	<50nm	Manual: Beam Tilt (coarse) Corrector (fine)
C3	3 rd	Spherical Aberration Coefficient	0-3um	Corrector
A3	3 rd	4-fold Astigmatism	<1um	Corrector
S3	3 rd	Star Aberration	<1um	Corrector



Precision vs Accuracy

- An appropriate specimen with enough density of heavy element particles on a low background support is needed in order to measure the aberrations.
- The CEOS software measures the sharpness of the edges of the particles (in all directions). Anything which affects that sharpness (drift, contamination etc) will invalidate the measurement.
- Magnification will affect the number of particles in the field of view (accuracy) as well as the detail in them (precision).
- A balance between accuracy and precision is needed for a good measurement of aberration coefficients.
- Mag of 400K-600K, 8C probe (30pA), 20um C2 aperture.



Tuning Methodology

- You must correct all first order aberrations before tuning second order aberrations.
- You must correct all second order aberrations before tuning third order aberrations.
- After a 3rd order tune first order aberrations will need correcting.
- Repeat the above tuning cycle (1st, 2nd, 3rd, 1st, 2nd.
 ...etc) until all aberrations are within target range.
- The Ronchigram will grow in size and uniformity as aberrations are tuned out.





Manually Aligning Ronchigram

 Degauss twice then correct C1 and A1 and coarse alignment of B2 (coma) using the Ronchigram. Note you can manually correct B2 to perhaps 100nm. The software will improve this to ca 20nm.







Manually Correcting 1st Order Aberrations

Ensure that the beam is centred in the HAADF detector (lower the magnification to 20kx and use projector lens shifts to centre the illumination, then return to higher mag. If off-centre, large tilts (24-27mrads) used for 3rd order correction (later), may run the beam into the HAADF detector.



Corrector Tune of 2nd Order Aberrations

STEM CsCorrector GUI (service) V2.95p12 built |

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Ensure all (or nearly all) of the tableau measurements are used. If more than 3 or 4 are rejected – the result is unreliable. Discard and run again.

Tab pressed. # 1 Cl: 2.396nm Al: 5.258nm / +26.5deg # 2 Cl: 5.329nm Al: 5.355nm / -18.2deg # 3 Cl: 9.662nm Al: 10.09nm / 87.4deg # 4 Cl: 7.85nm Al: 9.438nm / -102.7deg # 5 Cl: 5.553nm Al: 4.302nm / -28.8deg # 6 Cl: 3.14nm Al: 2.84nm / -115.6deg # 7 Cl: 3.058nm Al: 2.797nm / -54.2deg # 8 Cl: -954pm Al: 3.174nm / -11.7deg # 9 Cl: -3.159nm Al: 4.179nm / -54.6deg #10 Cl: 1.528nm Al: 7.241nm / -13.8deg #11 Cl: -482.1pm Al: 1.864nu / +35deg #12 Cl: 3.34nm Al: 3.839nm / -73deg #13 Cl: 7.517nm Al: 6.981nm / -25.9deg #14 Cl: 2.867nm Al: 4.579nm / -12.8deg #15 Cl: 4.92nm Al: 2.533nm / -43.2deg #16 Cl: 1.896nm Al: 9967pm / +68.2deg #17 Cl: 2.246nm Al: 3.192nm / -27.4deg #18 Cl: 2.204nm Al: 2.937nm / -27.4deg #14 Cl: 2.204nm Al: 2.937nm / -27.4deg	signal mean: 2252cnts signal mean: 2515cnts signal mean: 2379cnts signal mean: 2236cnts signal mean: 2120cnts signal mean: 2100cnts signal mean: 2170cnts signal mean: 2384cnts signal mean: 2653cnts signal mean: 2822cnts signal mean: 2895cnts signal mean: 2811cnts signal mean: 2677cnts signal mean: 2136cnts signal mean: 2136cnts signal mean: 2266cnts signal mean: 2475cnts signal mean: 2251cnts	uf uf uf <	dard Tableau and mrad tilt angle. ve you reliable 2 nd
#18 Cl: 2.204nm Al: 2.937nm / -27.4deg dTime. 73773s Date. Fri Jan 5 01.53.42 lst order measured! (not used:)	signal mean: 2251cnts 2018	0.000 extra -16.785 Dipol22X -8.115 Dipol22X	ration values.
Sail: 3.897nm Sused: 3.897nm (1.122%) Cl: 2.3nm (95%: 4.9nm) Al: 3.69nm / +7.7deg (95%: 6.06nm) A2: 24.24nm / -156deg (95%: 45.7nm) P2: 61 61nm / +44.5deg (95%: 29.2nm)	A2=24 +/- 48nm OK B2=62 +/- 29nm Not O	K +24.132 BTILEX Y +24.132 BTILEX Y +0.000 extra K +0.000 extra K +0.000 extra	B rd order and Jes.
C3: 2.322um (95%: 2.3.21m) A3: 707.3nm / -152.2deg (95%: 1.74um) S3: 1.474um / +111.2deg (95%: 753nm) A4: 50.33um / +74.8deg (95%: 72.7um)	Correct B2 by clicking (OK	
Btn 'Accept Aberr' pressed. Btn 'B2' pressed. Π	and pressing the B2 bu	itton	

Corrector Tune of 2nd Order Aberrations ctd

- Continue tuning 2nd order aberrations until the A2 and B2 values are within the target range (both <50nm).
- Only then move on to correcting 3rd order aberrations.

lst (order mea	ลรเ	ured! (not	used:)
Sall	: 3.14lnr	n S	Sused: 3.14	lnm (0	0.9042%)
Cl:	8.456nm			(95%:	2.68nm)
Al:	3.064nm	/	-35.9deg	(95%:	5.68nm)
A2:	29.99nm	/	-139.2deg	(95%:	42.8nm)
B2:	25.86nm	/	-50.9deg	(95%:	19.9nm)
C3: ·	-968.lnm			(95%:	1.08um)
A3:	507.6nm	/	+33deg	(95%:	1.63um)
S3:	350.6nm	/	+127.9deg	(95%:	614nm)
A4:	44.9lum	/	+121.3deg	(95%:	68.lum)
Π					

Target Values C1 5-10nm A1 5nm A2 <50nm B2 <50nm Ignore 3rd order



Corrector Tune of 3rd Order Aberrations

If more than 2 or 3 measurements are Rejected, run the tableau again. Focus on fixing A3 and S3 (ignore 1st and 2nd order) C3 will bounce around – change C3 at the end when you have a feel for the typical value.

	#10	C1:	5.43nm	Al:	€.197nm	/	- 49.	3deq	siqnal	mean:	2132cnts
	#11	C1:	6.582nm	Al:	3.607nm	/	- 37.	ldeg	signal	mean:	2215cnts
	#12	C1:	3.887nm	Al:	3.492nm	/	-31.	7değ	signal	mean:	2489cnts
	#13	C1:	6.235nm	A1:	3.924nm	/	- 39.	8deg	signal	mean:	2348cnts
	#14	C1:	7.29nm	A1 :	5.551nm	/	- 34.	8deg	signal	mean:	2426cnts
	#15	C1:	6.162nm	A1	9.505nm	/	-26.	ldeg	signal	mean:	2248cnts
	#16	C1:	678pm	A1	3.233nm	/	- 25.	5deg	signal	mean:	2123cnts
	#17	C1:	2.658nm	A1 :	5.461nm	/	-	2deg	signal	mean:	2197cnts
	#18	C1:	2.711nm	A1 :	2.936nm	/	-12.	5deg	signal	mean:	2487cn‡s
	#19	C1:	4.864nm	AL:	5.952nm	/	-21.	6deg	signal	mean:	2811crts
	#20	C1:	5.817nm	41:	2.747nm	/	- 36.	2deg	signal	mean:	2848.nts
	#21	C1:	3.654nm	1:	6.381nm	/	-74.	ldeg	signal	mean:	262/cnts
	#22	C1:	3.74nm	A1:	3.508nm	/	- 65.	9deg	signal	mean:	2169cnts
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	sati	ι: Ζ.	oı∕nm Su	sed:	2.61/NM	(0,	7534	P\$)			
	Cl:	4.5	44nm		(95	%: 2	2.65n	m)			
	Al:	2.7	54nm /	- 3	ldeg (95	%: 4	1.52n	m)	(nake	anv
	A2:	31.	76nm /	-6	5deg (95	%: 4	45.ln	m)		nanc	2 uny
ſ	B2:	17	.2nm /	6.	5deg (05	8: 4	10.2n	m)	chang	res a	t the e
I	C3:	- 869	.9nm		(95)	%: 2	2.68u	im) '	chung	,cs u	t the c
I	A3:	690	.5nm /	-69.	5deg (95	%∶	771n	(m)		212	lithin c
					_ 1				ΔΫ — (JK \X	/
1	S3:	638	.8nm /	+21.	6deg (95	%:	282n	im) 4	A3 – (JK W	
l	S3: A4:	638 25,	.8nm / 22um /	+21. +17.	6deg (95 6deg (95	%: *; ∠	282n	m) (A3 – (S3 – (JK M `an b	num e
l	S3: A4: D4:	638 25 7.7	.8nm / 22um / 89um /	+21. +17. +73.	6deg (95 6deg (95 1deg (95	%: %: 2 %: 1	282n 24.4u 3.5u	m) m) m)	A3 — (S3 — (Can b	be fixe
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l	S3: A4: D4: B4: C5:	638 25. 7.7 13.	.8nm / 22um / 89um / 22um / - 2mm	+21. +17. +73. 138.	6deg (95 6deg (95 1deg (95 6deg (95 (95	%: %: 2 %: 1 %: 2 %: 3	282n 24.40 13.50 27.10 3.32m	im) im) im) im)	A3 – (S3 – (Press	Can b OK t	be fixe then S
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ι	S3: A4: D4: B4: C5: A5: Btn Btn	638 25. 7.7 13. 1.0 'Acc 'S3'	.8nm / 22um / 89um / 22um / - 2mm 13mm / ept Aber pressed	+21. +17. +73. 138. 138. +8 r' p	6deg (95 6deg (95 1deg (95 6deg (95 6deg (95 4deg (95 ressed.	%: 2 %: 1 %: 2 %: 3 %:	282n 24.4u 23.5u 27.1u 3.32m 885u	m) m) m) m) m)	A3 – (S3 – (Press	DK w Can b OK t	chen S



After Correcting 3rd order Aberrations

- Correct whichever is the worst aberration (A3 or S3). Corrections will ruin 1st and 2nd order alignments.
- Correct these by generating a Ronchigram and manually correct C1 (focus), A1 (2-fold astig) and B2 (coma).



After correcting S3: bad coma



Correctly tuned Ronchigram





Tune 1	Tune 2	Tune 3

After Completing the nth Tune

- After fixing 1st order aberrations, run one or more Standard Tableaux and fix 2nd order.
- Then run an Extended Tableaux and fix third order aberrations Repeat the tuning cycle to converge on target values. An unstable microscope will not converge.

lst order measured! (not used:)						
Sall: 3.913nm Sused: 3.913nm (1.126%)						
Cl:	2.614nm		(95%:	3.97nm)		
Al:	1.813nm / +4	5.5deg	(95%:	6.74nm)		
A2:	65.7lnm / +12	22.6deg	(95%:	67.5nm)		
B2:	36.21nm / +5	3.4deg	(95%:	60.lnm)		
C3:	3.034um	, i	(95%:	4.02um)		
A3:	461.2nm / -6	64.9deg	(95%:	1.15um)		
S3:	552.lnm / +7	2.6deg	(95%:	422nm)		
A4:	42.84um / +11	.7.2deg	(95%:	36.5um)		
D4:	11.48um / +6	52.6deg	(95%:	20.2um)		
B4:	20.74um / -9)8.2deg	(95%:	40.6um)		
C5:	599.6um	-	(95%:	4.97mm)		
A5:	1.602mm / +10)4.5deg	(95%:	1.32mm)		
		2				

- Only trust 1st and 2nd order values from a Standard Tableau.
- Only trust 3rd order values from an Extended Tableau – results shown left.
- Here A2 is higher than target (<50nm) ignore it (note the large error). The value in the previous Standard Tableau was <50nm.
- C3 bounced around a bit during tuning, but the average was 3um which is on target.
- A3 and S3 are <1um which is fine.
- The Ronchigram appearance/size is more important than the numbers.



The Goal of Tuning

• The aim of tuning the corrector is to produce a very large aberration-free region within a symmetric Ronchigram.



Closing Remarks.

- Minimise the amount of work the software has to do during tuning, by manually correcting focus (C1), 2-fold astigmatism (A1) and coma (B2) as well as possible, before asking the software to correct those values.
- 2. Monitor the hexapole values HpolX and HpolY, especially when correcting A2 (3-fold astitgmatism). Keep the values to within +/- 10um. If the values become very large, then heating/hysteresis may result in an unstable tune. If the values move slightly outside the +/-10um range during tuning eg +/-15um, then avoid changing them immediately, as they may move back towards zero during subsequent tunes. However, if they move outside that range significantly, reset them by choosing Reset A2. This may mess up the tune somewhat so go back to stage 1 (Manual correction) and proceed from there.
- 3. Low voltage (60-80kV). Good tunes are much more difficult at low voltage, as minor variances have a much bigger effect. I routinely switch to 80kV on Friday pm. Allow the weekend to magnetically and thermally equilibrate, then tune the following Monday. However, I find this tune is not very stable and by Mon pm/Tues the Ronchigram has reduced in size. I reserve all the low resolution work, such as EDS mapping, for Mon and Tues. Then on Wed am I again retune the corrector. This results is a very stable tune for the remainder of the week. I reserve all high resolution work eg graphene ring imaging from Wed-Fri. In general, 200kV tunes are much easier. If I tune on a Monday (after switching to 200kV on Friday), the tune is very stable thereafter and will not need to be redone.

- 4. Microscope stability is critically important when tuning. Beam shower the specimen – there can be no contamination occurring during tuning. Always degauss (Lens Relax) the column twice before attempting a tune. Ensure the microscope is at standard focus and adjust the height to focus. Large changes in specimen height can result in subsequent focus drift. Ideally complete all major stage and height adjustments the night before tuning, to allow settling. At the start of tuning, monitor the focus and astigmatism for 30s or more to ensure that it is not changing. If it is, give it 30mins settling time and try again.
- 5. For high performance STEM, avoid using Low Mag mode if humanly possible. Low Mag mode turns off the objective lens (1kW of power). If you must use Low Mag – eg to find a FIB section, switch into Low Mag, find the region as quickly as possible (<20s), then switch back out immediately. In Low Mag mode the objective lens begins to cool, causing thermal drift. After using Low Mag, degauss the column (twice). DO NOT use Low Mag within 1hr of tuning. Even after degaussing, the objective lens may still be (thermally) unstable for 30 or more minutes.
- 6. When doing routine STEM, if you change spot size, the condenser lens crossover will move (relative to the corrector) and the Ronchigram will be degraded. Degauss the column twice then manually correct the A1, C1 and B2 in the Ronchigram. If you have a cold FEG microscope an alternative approach to changing spot size is to change the FEG extraction voltage, to change the probe current. Here the condenser lens crossover does not move (much) and the Ronchigram will not a retune unless doing high res.

